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APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.		
10/789,994	03/02/2004	Jenspeter Rau	0928.0032C	9673		
27896 75	90 09/21/2006		EXAM	EXAMINER		
•	PIRO & FINNAN, LLC CH BOULEVARD	ROSASCO, S	ROSASCO, STEPHEN D			
SUITE 400	CH BOULEVARD	ART UNIT	PAPER NUMBER			
ROCKVILLE, MD 20850			1756			
			DATE MAILED: 09/21/2000	DATE MAILED: 09/21/2006		

Please find below and/or attached an Office communication concerning this application or proceeding.

Office Action Summary		Applicati	on No.	Applicant(s)				
		10/789,9	94	RAU, JENSPETE	RAU, JENSPETER			
		Examine	r	Art Unit	<u> </u>			
		Stephen I		1756				
The MAILING DATE of this communication appears on the cover sheet with the correspondence address Period for Reply								
A SHORTENED STATUTORY PERIOD FOR REPLY IS SET TO EXPIRE 3 MONTH(S) OR THIRTY (30) DAYS, WHICHEVER IS LONGER, FROM THE MAILING DATE OF THIS COMMUNICATION.  - Extensions of time may be available under the provisions of 37 CFR 1.136(a). In no event, however, may a reply be timely filed after SIX (6) MONTHS from the mailing date of this communication.  - If NO period for reply is specified above, the maximum statutory period will apply and will expire SIX (6) MONTHS from the mailing date of this communication.  - Failure to reply within the set or extended period for reply will, by statute, cause the application to become ABANDONED (35 U.S.C. § 133). Any reply received by the Office later than three months after the mailing date of this communication, even if timely filed, may reduce any earned patent term adjustment. See 37 CFR 1.704(b).								
Status								
1)⊠	Responsive to communication(s) filed on	14 June 2004						
	This action is <b>FINAL</b> . 2b)⊠ This action is non-final.							
′—	Since this application is in condition for allowance except for formal matters, prosecution as to the merits is							
	closed in accordance with the practice under <i>Ex parte Quayle</i> , 1935 C.D. 11, 453 O.G. 213.							
Disposition of Claims								
4) 又	☑ Claim(s) <u>1-12</u> is/are pending in the application.							
	4a) Of the above claim(s) is/are withdrawn from consideration.							
	5) Claim(s) is/are allowed.							
· · · · · · · · · · · · · · · · · · ·	6)⊠ Claim(s) <u>1-12</u> is/are rejected.							
	Claim(s) is/are objected to.							
	Claim(s) are subject to restriction and/or election requirement.							
Application Papers								
·· _ ·								
9) The specification is objected to by the Examiner.								
10) The drawing(s) filed on <u>02 March 2004</u> is/are: a) accepted or b) objected to by the Examiner.								
Applicant may not request that any objection to the drawing(s) be held in abeyance. See 37 CFR 1.85(a).								
Replacement drawing sheet(s) including the correction is required if the drawing(s) is objected to. See 37 CFR 1.121(d).  11) The oath or declaration is objected to by the Examiner. Note the attached Office Action or form PTO-152.								
_	nder 35 U.S.C. § 119							
<ul> <li>12) Acknowledgment is made of a claim for foreign priority under 35 U.S.C. § 119(a)-(d) or (f).</li> <li>a) All b) Some * c) None of:</li> <li>1. Certified copies of the priority documents have been received.</li> <li>2. Certified copies of the priority documents have been received in Application No.</li> <li>3. Copies of the certified copies of the priority documents have been received in this National Stage application from the International Bureau (PCT Rule 17.2(a)).</li> <li>* See the attached detailed Office action for a list of the certified copies not received.</li> </ul>								
Attachment	(s)							
Notice of References Cited (PTO-892)  Notice of Draftsperson's Patent Drawing Review (PTO-948)  Information Disclosure Statement(s) (PTO/SB/08)  Paper No(s)/Mail Date			4) Interview Summa Paper No(s)/Mail 5) Notice of Informa 6) Other:	Date				

## **Detailed Action**

The following is a quotation of the appropriate paragraphs of 35 U.S.C. 102 that form the basis for the rejections under this section made in this Office action:

A person shall be entitled to a patent unless -

(e) the invention was described in (1) an application for patent, published under section 122(b), by another filed in the United States before the invention by the applicant for patent or (2) a patent granted on an application for patent by another filed in the United States before the invention by the applicant for patent, except that an international application filed under the treaty defined in section 351(a) shall have the effects for purposes of this subsection of an application filed in the United States only if the international application designated the United States and was published under Article 21(2) of such treaty in the English language.

Claims 1-12 are rejected under 35 U.S.C. 102(e) as being anticipated by Okoroanyanwu et al. (6,764,808).

Okoroanyanwu et al. teach an integrated circuit fabrication process, the process comprising: exposing a photoresist material provided including arylalkoxysilane over a substrate to a first radiation at a first lithographic wavelength; selectively transforming a top portion of the material in accordance with a pattern provided on a mask or reticle; and exposing the photoresist material to a second radiation at a second lithographic wavelength, wherein the first lithographic wavelength is shorter than the second lithographic wavelength and the transformed top portion of the photoresist material being non-transparent to the second radiation.

And wherein the first lithographic wavelength is selected from a wavelength including 157 nm, 126 nm, and 13.4 nm.

And wherein the second lithographic wavelength is selected from a wavelength including 365 nm, 248 nm, and 193 nm.

And wherein the exposing step with the first radiation is performed before the exposing step with the second radiation.

Claim 1 is rejected under 35 U.S.C. 102(e) as being anticipated by Wijnaendts et al. (US 20030031956 A1).

Wijnaendts et al. teach (see claims 6-8), a lithographic process wherein, after a first exposure step and subsequent development and formation of a first set of structures, a second exposure step is carried out in which the exposure is carried out with a predetermined displacement, and a second set of structures is produced having a desired offset relative to the first set.

And wherein the displacement for the second exposure step is chosen such that after final development, the second set of structures are situated in intermediate spaces formed between adjacent structures of the first set during the first exposure step.

And wherein, after a first exposure step and subsequent development and formation of a first set of structures, a second exposure step is carried out without an offset, and a second set of structures is produced precisely superimposed on the first set of structures.

Art Unit: 1756

## Conclusion

Any inquiry concerning this communication or earlier communications from the Examiner should be directed to Stephen Rosasco whose telephone number is (571) 272-1389. The Examiner can normally be reached Monday-Friday, from 8:00 AM to 4:30 PM. The Examiner's supervisor, Mark Huff, can be reached on (571) 272-1385. The fax phone number for the organization where this application or proceeding is assigned is (571) 273-8300.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

S. Rosasco

Primary Examiner Art Unit 1756

S.Rosasco 09/15/06